

1/6/04

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of

STUART D.HELLRING, et al.

Serial No.: 10/627,775

Filed: July 28, 2003

Title: PROCESS FOR REDUCING
DISHING AND EROSION
DURING CHEMICAL MECHANICAL:
PLANARIZATION

PATENT APPLICATION

Group Art Unit: 3723

Examiner:

Docket No: 1780A1

SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT

MAIL STOP: AMENDMENT

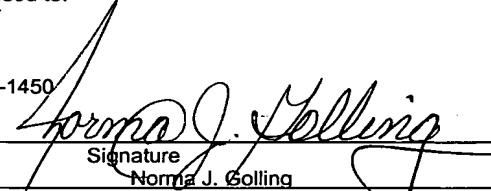
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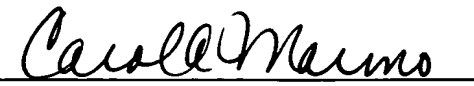
Sir:

The documents listed on the attached Form PTO-1449 are brought to the attention of the United States Patent and Trademark Office with respect to the application identified above in accordance with the provisions of 37 CFR 1.56, 1.97, and 1.98. These documents were cited in the International Search Report for the related International Application No. PCT/US03/24286 filed August 1, 2003. Copies of the International Search Report and the documents listed are enclosed herewith.

I hereby certify that this correspondence is being deposited with the United States Postal Service as first class mail in an envelope addressed to:	
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on June 24, 2004	
Date	Signature Norma J. Colling
Typed or Printed Name of Person Signing Certificate	

It is requested that the Examiner consider these documents and that it be made of record in the application.

Respectfully submitted,


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Pittsburgh, Pennsylvania
June 23, 2004

		Atty. Docket No. 1780A1	Serial No. 10/627,775
LIST OF CITATIONS BY APPLICANT (Use several sheets if necessary)		Applicant: Stuart D. Hellring, et al.	
		Filing Date: July 28, 2003	Group Art Unit: 3723

U.S. PATENT DOCUMENTS

Init.	Document No.	Date	Name	Class	Subclass	Filing Date if appropriate
AA	5,885,334	03/23/99	Tetsuo and Hara	106	3	
AB	5,954,975	09/21/99	Cadien and Feller	216	38	
AC	5,985,748	11/16/99	Watts, et al.	438	622	
AD						
AE						
AF						
AG						
AH						
AI						
AJ						
AK						

FOREIGN PATENT DOCUMENTS

	Document No.	Date	Country	Class	Subclass	Translation Yes No
AL	EP 0 684 634 A2	04.05.1995	EP			
AM	EP 1 085 067 A1	30.11.1999	EP			
AN	WO 00/00561	06.01.2000	PCT			
AO	WO 01/78128 A2	18.10.2001	PCT			
AP	WO 02/102920 A1	27.12.2002	PCT			

OTHER CITATIONS (Including Author, Title, Date, Pertinent Pages, Etc.)

AR	US 2002/0068451 A1, Semiconductor Device Production Method, June 6, 2002
AS	
AT	

Examiner	Date Considered
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*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.
 SUBSTITUTE DISCLOSURE STATEMENT FORM (PTO 1449)